# Monthly LabAdviser update: 17/2 2014

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| Updated Subject  | Contributor | Link to the updated pages |
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| **Cleanroom naming**Overview of the new cleanroom naming – this is only in the start-up phase of being implemented in LabAdviser and LabManager | **Danchip** | [Cleanroom naming](http://labadviser.danchip.dtu.dk/index.php/Main_Page#Cleanroom_naming) |
| **Deposition of NiV**New page | **Katharina Nilson @Danchip** | [Deposition\_of\_NiV](http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Thin_film_deposition/Deposition_of_NiV) |
| **Stress measurements**Measure at least along 70% of the wafer length | **Katharina Nilson @Danchip** | [Stress\_measurement](http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Characterization/Stress_measurement) |
| **Drop Shape Analyzer**New page | **Thomas Anhøj @Danchip** | [Drop Shape Analyzer](http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Characterization/Drop_Shape_Analyzer) |
| **MVD – antistiction coating**New process info and page update | **Thomas Anhøj @Danchip** | [Antistiction\_Coating](http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Thin_film_deposition/Antistiction_Coating)[MVD](http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Thin_film_deposition/MVD) |
| **Furnace nitride**Updated page | **Pernille V. Larsen @Danchip** | [Deposition\_of\_Silicon\_Nitride\_using\_LPCVD](http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Thin_film_deposition/Deposition_of_Silicon_Nitride/Deposition_of_Silicon_Nitride_using_LPCVD) |
| **Furnace poly**Updated page | **Pernille V. Larsen @Danchip** | [Furnace\_LPCVD\_PolySilicon](http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Thin_film_deposition/Furnace_LPCVD_PolySilicon) |
| **Isotropic dry SiO2 etch**-in the Plasma Asher | **Berit and Lis @Danchip** | [Isotropic SiO2 etch in the plasma asher](http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Etch/Etching_of_Silicon_Oxide/SiO2_etch_using_Plasma_Asher#SiO2_can_be_etched_in_the_Plasma_Asher_using_CF4) |
| **AOE**Slow SiO2 etch | **Berit G. Herstrøm @Danchip** | [Slow\_etch\_of\_SiO2\_with\_resist\_as\_masking\_material](http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Etch/Etching_of_Silicon_Oxide/SiO2_etch_using_AOE#Slow_etch_of_SiO2_with_resist_as_masking_material_-_with_direct_clamping) |
| **ICP metal**Slow SiO2 etch | **Berit G. Herstrøm @Danchip** | [ICP metal silicon\_oxide](http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Etch/ICP_Metal_Etcher/silicon_oxide) |
| **ASE equipment page**Update | **Jonas M. Lindhard @Danchip** | [ASE equipment page](http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Etch/ASE_%28Advanced_Silicon_Etch%29) |
| **EVC profiler** | **Jesper Hanberg @Danchip** | [III-V\_ECV-profiler](http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/III-V_Process/characterisation/III-V_ECV-profiler) |
| **X-ray diffractometer** | **Jesper Hanberg @Danchip** | [X-Ray\_Diffractometer](http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/III-V_Process/characterisation/X-Ray_Diffractometer) |
| **Polisher/lapper** | **Jesper Hanberg @Danchip** | [Polishing\_machine](http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Back-end_processing/Polishing_machine) |
| **Resist pyrolysis furnace**Updated page | **Pernille V. Larsen @Danchip** | [Resist\_Pyrolysis\_Furnace](http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Thermal_Process/Resist_Pyrolysis_Furnace#Resist_Pyrolysis_Furnace) |
| **Hummer and Balzer sputter coaters** now in LabAdviser | **Pernille V. Larsen and****Katharina Nilson @Danchip** | [Sputter coaters](http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Thin_film_deposition/Sputter_coater) |
| **HMDS**The HMDS section has been updated | **Thomas Anhøj @Danchip** | [HMDS](http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Lithography/Pretreatment#HMDS) |
| **XPS**Updated page with new subpages | **Katharina Nilson @Danchip** | [XPS-ThermoScientific](http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Characterization/XPS#XPS-ThermoScientific) |
| **PECVD**Page revised after PECVD1 has been decommissioned and PECVD2 has taken over. | **Berit G. Herstrøm @Danchip** | [PECVD](http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Thin_film_deposition/PECVD) |
| **SEM Supra 60VP**Added to SEM overview page | **Jomas M. Lindhard @Danchip** | [SEM:\_Scanning\_Electron\_Microscopy](http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Characterization/SEM%3A_Scanning_Electron_Microscopy) |
| **Wordentech**Updated page | **Katharina Nilson @Danchip** |  |
| **Alcatel**Updated page | **Katharina Nilson @Danchip** |  |
| **III-V profiler**Updated page | **Katharina Nilson @Danchip** |  |
| **Physimeca**Updated page | **Katharina Nilson @Danchip** |  |
| **III-V Dielectric evaporator**Updated page | **Katharina Nilson @Danchip** |  |
| **Profiler**Updated page | **Katharina Nilson @Danchip** |  |
| **Critical point dryer**Updated page | **Katharina Nilson @Danchip** |  |
| **Multisource PVD**Updated page | **Katharina Nilson @Danchip** |  |
| **Lesker sputter tool**Updated page | **Katharina Nilson @Danchip** |  |
| **Black Magic PECVD**Updated page | **Katharina Nilson @Danchip** |  |
| **Deposition of Palladium**Updated page | **Katharina Nilson @Danchip** |  |
| **Optical profiler**Updated page | **Pernille V. Larsen @Danchip** |  |
| **AOE**Updated page | **Berit G. Herstrøm****@Danchip** |  |
| **Thickness measure** | **Mikkel Mar @Danchip** |  |
| **Dektak XTA and Dektak 8** | **Katharina Nilson @Danchip** |  |
| **Nanoman** | **Berit Herstrøm @Danchip** |  |
| **Disco Saw** | **Helle and Jesper @Danchip** |  |
| **Flip-chip bonder** | **Karen Birkelund @Danchip** |  |
| **Probe station** | **Mikkel Mar @Danchip** |  |
| **Atomika SIMS** | **Jonas M. Lindhard @Danchip** |  |
| **FilmTek** | **Berit G. Herstrøm @Danchip** |  |